Presentations (Invited) **(**Apr.2012 - Mar. 2013)

1. H. Ohmori: "The UltraFabrication: ELID Grinding Technologies", The 9th Cooperative and Joint international conference on Ultra-precision Machining Process, in conjunction with The 7th Conference of Ultra-Precision (ELID) Technology Research Group, Jeju, Korea, March, 2013
2. K. Sugioka, S. Wu, and K. Midorikawa: "Double-pulse irradiation of ultrafast laser for high-efficiency glass microwelding", SPIE Int. Sypm. on Laser Applications in Microelectronic and Optoelectronic Manufacturing XVIII (LAMOM XVIII), San Francisco, USA, Feb. (2013).
3. K. Ishibashi, A. Hida: "Optical emission and control in carbon nanotube quantum dots", The Sweden-Japan Workshop on Quantum Nano-Physics and Electronics (QNANO2013), Tokyo, Japan, Jan. 13-14(2013).
4. E. J. Takahashi P. Lan, and K. Midorikawa: "Energy scaling of isolated attosecond pulses", The 7th Asian Symposium on Intense Laser Science (ASILS7), Tokyo, Japan, Nov. (2012).
5. E. J. Takahashi: "Gigawatt-scale isolate attosecond pulses by high-order harmonic", 10th Asian International Seminar on Atomic and Molecular Physics, Taipei, Taiwan, Oct. (2012).
6. Y. Cheng, Z. Z. Xu, K. Sugioka, and K. Midorikawa, "Construction of microfluidic biochips with enhanced functionalities using 3D femtosecond laser direct writing", 20th Int. Conf. on Advanced Laser Technology (ALT' 12), Thun, Switzerland, Sept. (2012).
7. Y. Cheng, Y. Liao, Z. Z. Xu, K. Sugioka, and K. Midorikawa, "Femtosecond laser direct writing of 3D micro- and nanofluidics for bio-applications", 73rd Japan Society of Applied Physics Fall Meeting (International Symposium), Matsuyama, Japan, Sept. (2012).
8. Y. Cheng, Y. Liao, J. Song, Y. Shen, D. Chen, Zhizhan Xu, K. Sugioka, and K. Midorikawa, "Fabrication of integrated micro-nanofluidics embedded in glass with sub-50nm feature sizes", 2nd International Forum on Trends in Nano-Manufacturing, Suzhou, China, Sept. (2012).
9. Y. Nagata, T. Harada, M. Nakasuji, H. Kinoshita, and K. Midorikawa: "Development of highly spatial-coherent, 13.5-nm high-order harmonics for EUVL mask inspection using Coherent EUV Scatterometry Microscope", IEEE Photonics Conference 2012, California, USA, Sept. (2012).
10. Y. Cheng, Z. Z. Xu, K. Sugioka, and K. Midorikawa: "Construction of microfluidic biochips with enhanced functionalities using 3D femtosecond laser direct writing", 20th Int. Conf. on Advanced Laser Technology (ALT' 12), Thun, Switzerland, Sept. (2012).
11. K. Sugioka: "Femtosecond laser 3D micromachining for optofluidics fabrication", Optofluidcs 2012, Suzhou, China, Sept. (2012). **Plenary**
12. K. Midorikawa: "Generation of intense isolated attosecond pulses", The Workshop on Super Intense Laser-Atom Physics (SILAP 2012), Suzhou, China, Sept. (2012).
13. K. Sugioka, Y. Hanada, H. Kawano, I. S. Ishikawa, A. Miyawaki, and K. Midorikawa: "Femtosecond laser 3D micromachining for optofludics fabrication", The 8th International Conference on Photo-Excited Processes and Applications (ICPEPA-8), Rochester, USA, Aug. (2012).
14. K. L. Ishikawa: "Attosecond and femtosecond photoionization dynamics of He", the joint workshop of the 5th Asian Workshop on Generation and Application of Coherent XUV and X-ray Radiation (5th AWCXR) and the ISSP International Workshop on Coherent Soft X-ray Sciences, Kashiwa, Japan, June (2012)
15. H. Ohmori: "NANO-ELID Micro and UltraFabrication Technologies", Ultra-Precision Machining and Optic Lens Manufacturing Technology, Soul, Korea, June (2012).
16. K. Sugioka, K. Midorikawa, Y. Cheng, and Z. Xu: "High-performance laser processing using manipulated ultrashort pulses", 2012 Int. Conf. on High-Power Laser Ablation (HPLA 2012), Santa Fe, USA, May (2012).
17. H. Ohmori: "Current Status of R&D Activities on Microfabrication in RIKEN Group for Critical Component Development", The 6th MIRAI workshop, San Francisco, USA, May (2012).
18. K. Sugioka, and K. Midorikawa: "3D integration of functions inside glass by ultrafast laser", The 3rd

Shanghai-Tokyo Advanced Research Symposium on Ultrafast Intense Laser Science (STAR3), Odawara, Japan, May (2012).

19. K. Midorikawa: “Recent progress on high harmonic generation and application at RIKEN”, The 3rd Shanghai -Tokyo Advanced Research Symposium on Ultrafast Intense Laser Science (STAR3)”, Odawara, Japan, May (2012).
20. H. Ohmori: “Nanoprecision Micro-Structural Ultra Fabrication Technologies and Surface Functionalization”, The 2nd International Symposium on Micro/Nano Mechanical Machining, Matsushima, Japan, Apr. (2012).
21. H. Ohmori: “ELID, Micro and Ultra Fabrication Technologies”, The 2nd International Conference on Frontiers of Plasmonics, Chengdu, China, Apr. (2012).
22. H. Ohmori: “Effect and Applications of Nanodiamond in Nanoprecision Machining”, 2012 MRS Spring Meeting, San Francisco, USA, Apr. (2012).
23. K. Ishibashi: “Carbon nanotube quantum dots for teraherz detection”, Symposium L on Group 4 Photonics for Sensing and Imaging, 2012 MRS (Material Research Society) Spring Meeting, San Francisco, USA, Apr. (2012).
24. 永田 豊、原田哲男、木下博雄、緑川克美: “コヒーレントスキャトロメトリー顕微鏡用光源としての 13.5nm 高次高調波発生システムの開発” 、レーザー学会学術研究会第 33 回年次大会、姫路、1 月(2013).
25. 杉岡幸次, “レーザー加工分野の最新動向”, 浜松光技術活用研究会、１２月、浜松 (2012).
26. 杉岡幸次, “レーザ加工分野の最新動向”, 平成２４年光産業技術振興協会光産業動向セミナー、９月、東京 (2012).
27. 杉岡幸次, “超短パルスレーザーによるガラスの３次元加工”, 日本光学会光設計研究グループ研究会「光と新しい加工技術」、１１月、東京 (2012).
28. 杉岡幸次, “フェムト秒レーザー３次元加工技術とその応用”, レーザーシステムズセミナー、１１月、札幌 (2012).
29. 杉岡幸次, “レーザー加工の産業動向”, レーザーシステムズセミナー、１１月、札幌 (2012).
30. 杉岡幸次, “フェムト秒レーザー３次元加工とバイオチップ作製への応用”, 第５７回宇都宮大学オプティクス教育研究セミナー、１１月、宇都宮 (2012).
31. 高橋栄治：“ギガワット級単一アト秒パルス光源の開発と非線形光学研究への展開”、第 73 回応用物理学会学術講演会、松山、９月(2012).
32. 緑川 克美：“高次高調波による分子科学”、第６回分子科学討論会、東京、９月 (2012).
33. 杉岡幸次：“レーザ加工分野の最新動向”、平成２４年光産業技術振興協会光産業動向セミナー、東京、９月(2012).
34. 磯部圭佑：“時空間制御した非線形光学顕微分光法”、フォトニック信号処理セミナー、淡路、８月 (2012).
35. 杉岡幸次：“レーザ加工の産業動向”、光産業技術振興協会平成２４年度第２回多元技術融合光プロセス研究会、東京、８月(2012).
36. 杉岡幸次：“レーザーマイクロ･ナノ加工の基礎と最前線”、日本テクノセンターセミナー、東京、５月(2012).
37. 杉岡幸次：“超短パルスレーザー加工”、レーザーEXPO 2012 レーザー特別セミナー、横浜、４月(2012).
38. 杉岡幸次： “レーザー加工の基礎”, レーザーEXPO 2012 レーザー特別セミナー、横浜、４月(2012).